

MNE 2010 - 36th International Conference on Micro & Nano Engineering

Veranstaltung - MNE 2010 - 36th International Conference on Micro & Nano Engineering

Titel	MNE 2010 - 36th International Conference on Micro & Nano Engineering
Wann	So, 19. September 2010 - Mi, 22. September 2010

Beschreibung

MNE 2010 - 36th International Conference on Micro & Nano Engineering

Background Information

Micro- and Nano-Engineering (MNE) is an international conference on micro- and nano- fabrication and manufacturing using lithography and other nano-patterning related approaches. The Conference brings together engineers and scientists from all over the world to discuss recent progress and future trends in the fabrication, manufacturing and application of micro- and nano- structures and devices.

Scope of the Conference

1. Micro & Nano Lithography

- a. Nanoimprint Lithography
- b. Mask-Less Lithography
- c. Photon Lithography
- d. Electron and Ion Beam Lithography
- e. Materials for Micro and Nano Lithography

2. Micro & Nano Fabrication, Nano Engineering

- a. Nanofabrication with top-down and bottom-up approaches
- b. Pattern Transfer and Plasma etching
- c. Nanometrology
- d. Nanoelectronic / photonic devices
- e. Micro and Nanomanufacturing

3. Micro & Nano Fabrication for Life Sciences

- a. Micro & Nano fluidics, devices for biology, chemistry, medicine
- b. Micro & Nano Systems for biology, chemistry, medicine

4. Micro & Nano systems and their fabrication

MEMS, NEMS, Surface and bulk micro machining, 3D structures, stereolithography, new materials, sensors and actuators, M(O)EMS, RF-MEMS/NEMS, electromechanical passive devices, RF mechanical resonators...

Look [here](#) for more information.

Lokalität - Genova

Standort	Genova
Ortsname	Genova
Land	IT